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LIST OF SYMBOLS AND ABBREVATIONS

PCE	Power conversion efficiency
DSCs	Dye-sensitized solar cells
PE	Photoelectrode
CE	Counterelectrode
EL	Electrolyte
ТСО	Transparent conducting oxide
НОМО	The highest occupied molecular orbital
LUMO	The lowest unoccupied molecular orbital
СВ	conduction band
J _{sc}	Short-circuit current density
FF	Fill factor
V _{oc}	Open-circuit voltage
J	Current density
V	Voltage
P _{in}	Power of incident solar spectrum
P _{max}	Maximum power
J _{max}	Maximum current density
V _{max}	Maximum voltage
P _{theory} Cop	Theoretical power
LHE, Φ_{LH}	Light harvesting efficiency
SSA	Specific surface area
FTO	Fluorine-doped tin oxide
PEG	Polyethylene glycol
FE-SEM	Field-emission scanning electron microscopy
EY	Eosin-Y
Φ_{G}	Electron generation efficiency
Φ_{C}	Charge collection efficiency

EIS	Electrochemical impedance spectroscopy
R _s	Series resistance
R _{ct}	Charge transfer resistance
СРЕ	Constant phase element
R _{rec}	Recombination resistance
R	Gas constant
Т	Absolute temperature
F	Faraday's constant
J_0	Exchange current density
τ	Electron life time
\mathbf{f}_{peak}	The frequency at the maximum peak from the Bode phase plots
IPCE	Incident photon to current efficiency
C	Capacitor
EQE	External quantum efficiency
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ข้อความแห่งการริเริ่ม

- กระบวนการปรับปรุงพื้นผิวทางเกมีซึ่งประกอบด้วยกระบวนการแบบสารละลายและแบบไอ เชิงเกมีมีสักยภาพที่จะดัดแปลงฟิล์มพรุนซิงก์ออกไซด์สำหรับการประยุกต์ใช้ในเซลล์ แสงอาทิตย์ชนิดสีย้อมไวแสง
- การคัคแปลงพื้นผิวฟิล์มซิงก์ออกไซค์ด้วยกระบวนการไอเชิงเคมีได้ถูกสาธิตเป็นครั้งแรกใน งานวิจัยนี้สำหรับการเพิ่มประสิทธิภาพเซลล์แสงอาทิตย์ชนิดสีย้อมไวแสง
- การเพิ่มประสิทธิภาพเซลล์แสงอาทิตย์ชนิดสีย้อมไวแสงสามารถอธิบายได้โดยการเพิ่มการดูด ซับสีย้อมซึ่งเป็นผลมาจากการปรับปรุงฟิล์มพรุนซิงก์ออกไซด์



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STATEMENT OF ORIGINALITY

- 1. Chemical texturing processes including wet and vapor texturing process have ability to modify porous ZnO films for dye-sensitized solar cells.
- 2. Surface modification of porous ZnO films via chemical vapor texturing process is demonstrated for the first time in this work for power conversion efficiency enhancement of dye-sensitized solar cell.
- 3. The power conversion efficiency enhancement of dye-sensitized solar cells can be explained by increasing of dye adsorption due to modified porous ZnO films.



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